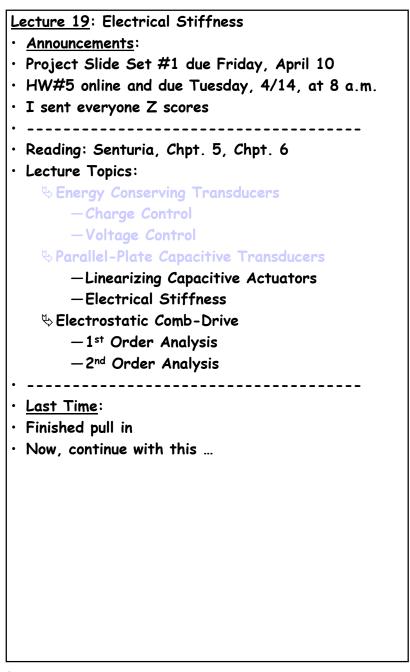
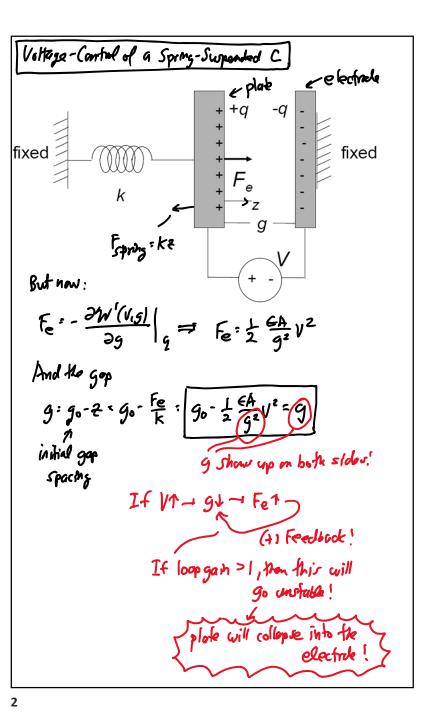
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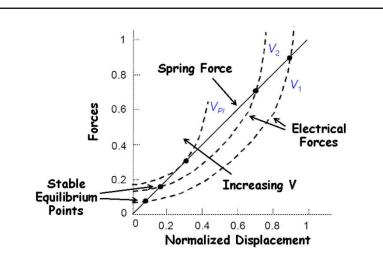


1

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Change: (to a stable gap) $q = \frac{\partial w'(v, g)}{\partial w} = Cv \sqrt{(as expected)}$ Stephility Analysis =) defermine under what condition refree-control will cause collepse of the plater: F_{hef} : F_e = F.spring: $\frac{AV^2}{2g^2} - k(g_o - g)$ F_e = F_{sorme} What happen when we change g by a small increment dg? I get on increment in the not otherachie force Fuet $\frac{df_{net}}{T} = \frac{\partial f_{net}}{\partial g} dg = \left[-\frac{GAV^2}{g^3} + k\right] dg$ If gi - dg= c), then for stubility, need Freq 1 -+ dfreq = (-) This must be (+)! - orknowice, the plater collegue Thus: $k > \frac{\epsilon A V^2}{g^3}$ (for a stuble uncellopped System) 3

Pultin Voltage & Pullin Gop VpI = Voltage @ which plater collapse 9m[♀] Gop @ The place goes unstable when: $k = \frac{\epsilon A V_{PT}^2}{2}$ (1) 9m $F_{\text{ref}} = 0 = \frac{\epsilon A V_{\text{PI}}^2}{2g_{\text{PI}}^2} - k(g_0 - g_{\text{PI}})$ (2) Inert (1) into (2): $0: \frac{\mathcal{C}AV_{PI}}{2g_{PI}} - \frac{\mathcal{C}AV_{PI}}{g_{PI}} (g_0 - g_{PI})$ $\frac{g_{0} g_{P1}}{g_{P1}} = \frac{1}{2} \rightarrow g_{0} = \frac{3}{2} g_{P1} \rightarrow g_{P1} = \frac{2}{3} g_{0}$ When the gap is driven by a $\frac{\text{Voltoge}}{\text{gap}} \rightarrow \text{collopse}$ $V_{PI} \leftarrow \frac{kg_{PI}^3}{\epsilon A} \rightarrow V_{PI} \leftarrow \frac{8}{\sqrt{27}} \frac{kg_0^3}{\epsilon A} \leftarrow \frac{1}{\epsilon A}$ this to prepart collopse Δ



Advantages of Electrostatic Actuators:

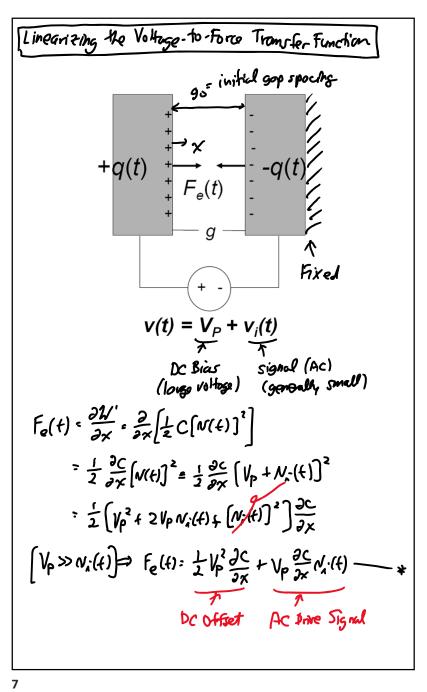
- Easy to manufacture in micromachining processes, since conductors and air gaps are all that's needed → low cost!
- Energy conserving \rightarrow only parasitic energy loss through I²R losses in conductors and interconnects
- Variety of geometries available that allow tailoring of the relationships between voltage, force, and displacement
- Electrostatic forces can become very large when dimensions shrink \rightarrow electrostatics scales well!
- Capacitive transducers are generally much stronger than piezoelectric at low frequencies, e.g., for many sensor applications
- Same capacitive structures can be used for both drive and sense of velocity or displacement
- Simplicity of transducer greatly reduces mechanical energy losses, allowing the highest Q's for resonant structures

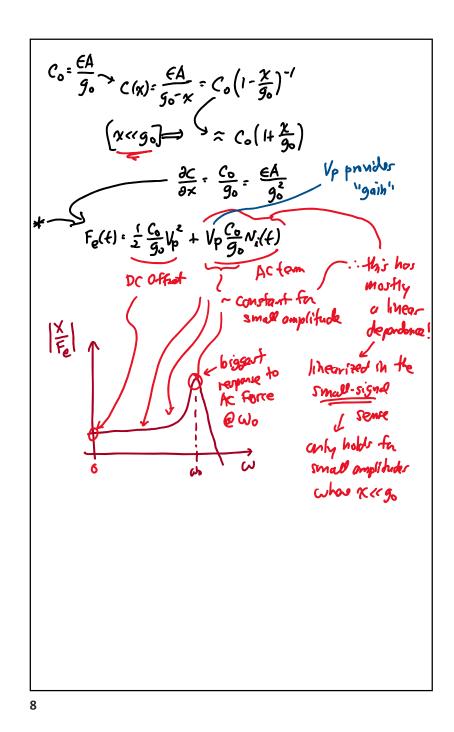


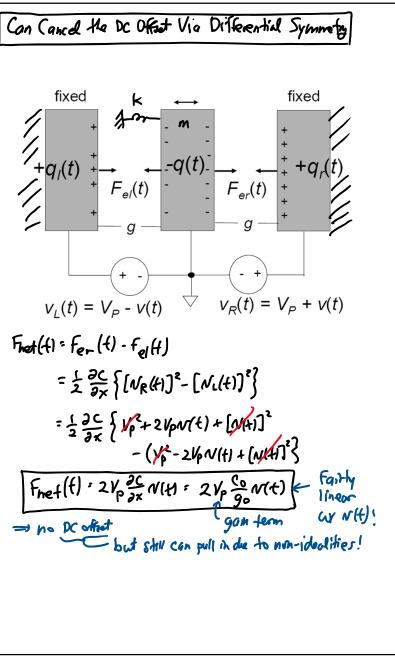
- Nonlinear voltage-to-force transfer function
- At high frequencies, relatively weak compared with other transducers (e.g., piezoelectric)
 - ♥ Due to higher mechanical stiffness and smaller electrode overlap area
 - ७ but things get better as dimensions scale with a fourth power dependence on gap spacing
- Go through variable naming convention in slide 21 of Lecture Module 12

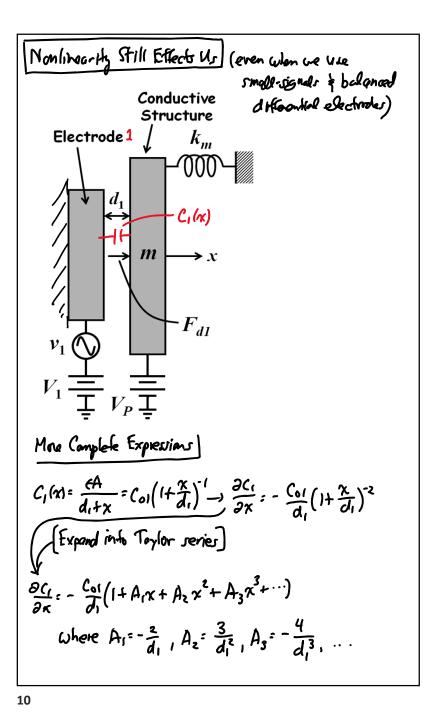
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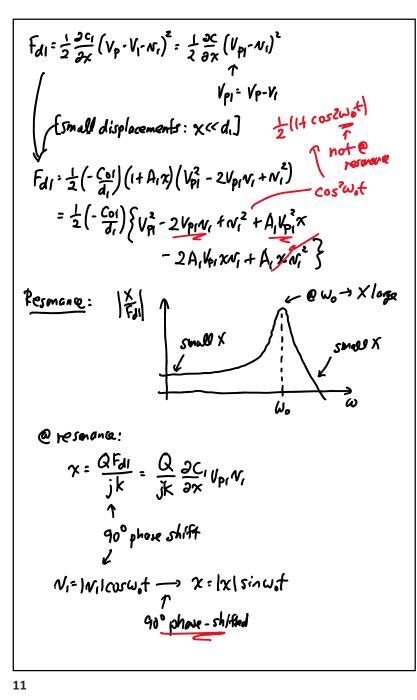


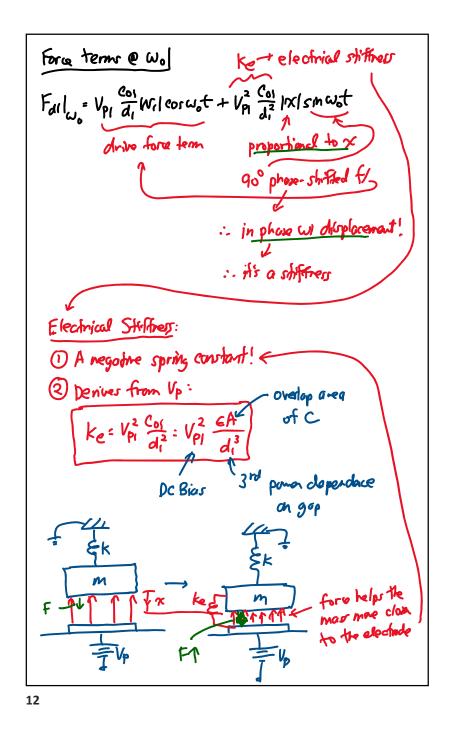




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$$ke \rightarrow Con \ \text{chech resonance frequency}
\left(\begin{array}{c} \omega_{o} \stackrel{a}{=} vod (an \ resonance freq. w(no Vp opplied (nominal resonance freq. (i.e., Vp:0) \\
\omega_{o} = \sqrt{\frac{K_{m}}{m}} \leftarrow \text{ane channed stiffers} \\
\omega_{o} = \sqrt{\frac{K_{m}}{m}} \leftarrow \sqrt{\frac{K_{m}}{m}} \leftarrow \sqrt{\frac{K_{m}}{m}} \left((-\frac{K_{e}}{K_{m}})^{2} \\
\overline{\omega_{o}} \\
\vdots \\
\overline{\omega_{o}} = \frac{\omega_{o} \left[1 - \frac{V_{Pl}}{p} \frac{EA}{M} \right]^{2}}{\sqrt{p}} \\
\text{new a function of DC Biar!} \\
(voltoge-Cantrollable)
\end{array}$$

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